

A B S T R A C TA METHOD OF MANUFACTURING A THIN FILM
MAGNETIC TRANSDUCER

A method of manufacturing a thin film magnetic transducer (10) comprises forming a first magnetic layer (26) on a non-magnetic substrate (12), forming a gap material layer (34) on the first magnetic layer (26), depositing a layer (36) having an aperture of a defined structure on the gap material layer (34) and forming a second magnetic layer (22) over the gap material layer and in the aperture. A sacrificial mask layer (18, 20) is deposited on the second magnetic layer (22) and in the aperture. The layer (36) having an aperture is removed exposing a portion of the gap material layer (34) and a portion of the first magnetic layer (26). The thin film magnetic transducer (10) is then exposed to a material removal process.

[Figure 2]

This Sheet Has Been Replaced

